FORM PTO-1449 (modified)
To: U.S. Department of Commerce
(PW FORM PAT-1449)
Patent and Trademark Office

INFORMATION DISCLOSURE STATEMENT
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M# Client Ref.

306781 P-0381.010-US

Applicant: Joeri LOF et al.

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Client Ref. FORM PTO-1449 (modified) Dkt. No. To: U.S. Department of Commerce (PW FORM PAT-1449) Patent and Trademark Office P-0381.010-US 306781 Applicant: Joeri LOF et al. INFORMATION DISCLOSURE STATEMENT BY APPLICANT Unknown Appin, No.: Filing Date: November 12, 2003 Group Art Unit: Unknown Examiner: Unknown Page Date: November 12, 2003 U.S. PATENT DOCUMENTS Filing Class Sub Date Name Document Examiner's Date Class (Family Name of First Inventor) MM/YYYY Number Initials* (if appropriate) CCC DDD EEE English Translation. FOREIGN PATENT DOCUMENTS Readily Abstract Inventor Name Available Country Date Document : MM/YYYY Number Enclose No Enclosed No FFFF GGG OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.) HHHB.J. Lin, "The Paths To Subhalf-Micrometer Optical Lithography", SPIE Vol. 922, Optical/Laser Microlithography (1988), pp. 256-269 IIIR G.W.W. Stevens, "Reduction of Waste Resulting from Mask Defects", Solid State Technology, August 1978, Vol.21 008, pp. 68-72 JJJRS. Owa et al., "Immersion Lithography; its potential performance and issues", SPIE Microlithography 2003, 5040-186, February 27, 2003 KKK S. Owa et al., "Advantage and Feasibility of Immersion Lithography", Proc. SPIE 5040 LLLRNikon Precision Europe GmbH, "Investor Relations – Nikon's Real Solutions", May 15, MMN H. Kawata et al., "Optical Projection Lithography using Lenses with Numerical Apertures Greater than Unity", Microelectronic Engineering 9 (1989), pp. 31-36 NNN J.A. Hoffnagle et al., "Liquid Immersion Deep-Ultraviolet Interferometric Lithography", J. Vac. Sci. Technol. B., Vol. 17, No. 6, November/December 1999, pp. 3306-3309 OOCB.W. Smith et al., "Immersion Optical Lithography at 193nm", FUTURE FAB International, Vol. 15, July 11, 2003 PPP H. Kawata et al., "Fabrication of 0.2µm Fine Patterns Using Optical Projection Lithography with an Oil Immersion Lens*, Jpn. J. Appl. Phys. Vol. 31 (1992), pp. 4174-4177 QQQG. Owen et al., "1/8µm Optical Lithography", J. Vac. Sci. Technol. B., Vol. 10, No. 6, November/December 1992, pp. 3032-3036 RRR SSS Ш UUU W

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Client Ref. Atty. FORM PTO-1449 (modified) Dkt. No. To: U.S. Department of Commerce (PW FORM PAT-1449) Patent and Trademark Office 306781 P-0381.010-US Applicant: Joeri LOF et al. INFORMATION DISCLOSURE STATEMENT BY APPLICANT Unknown Appln. No.: November 12, 2003 Filing Date: Group Art Unit: Unknown Examiner: Unknown .1 Page November 12, 2003 Date: U.S. PATENT DOCUMENTS Filing Class Sub Name Date Document Examiner's Date Class (Family Name of First Inventor) Number MM/YYYY Initials* (if appropriate) 212 117 Dhaka et al. 04/1971 3,573,975 AR 44 95 Stevens 03/1972 3,648,587 BR 311 430 Tabarelli et al. 08/1982 4,346,164 CR 430 326 Akeyama et/al. 08/1983 4,396,705 DR 355 30 Takanashi et el. 11/1984 4,480,910 ER 30 355 Tabareli/et al. 04/1985 4,509,852 FR 53 355 Rauschenbach et af 08//1991 5,040,020 GR 664 359 06/1992 Corie el al. 5,121,256 HR 355 53 Takahashi 08/1997 5,610,683 IR 53 355 d2/1998 Fukud**å** et ef 5,715,039 JR. 250 548 10/1998 Suwa 5,825,043 395 430 ds/1999 Batchelder 5.900,354 250 548 02/2001 Suwa 6,191,429 359 656 Hatano 05/2003 18.560,032 Translation **English** FOREIGN PATENT DOCUMENTS Readily **Abstract** Country Inventor Name Available Date Document MM/YYYY Number Enclosed No Endose No X Fukami et al. 09/1999 PCT WO 99/49504 U OR Tabarelli et al. 02/1981 Europe PR | EP 0023231 Miyake 03/1/991 Europe QR |EP 0418427 X. Murakimi et al. 09/2000 Europe EP 1039511 RR Hesse et al. 07/1985 German DD 224448 SR Kuch 02/1987 German DD 242880. TR Letellier FR 2474708 France 07/1981 UR Moriuchi JP 62-065326 03/1987 Japan VR Nakazawa 06/1987 Japan JP 62-121417 WR Nakasuji 06/1988 Japan JP 63-157419 OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.) EP Search Report for EP 02257938 dated September 25, 2003 YR M. Switkes et al., "Immersion Lithography at 157 nm", MIT Lincoln Lab, Orlando 2001-1, December 17, 2001 M. Switkes et al., "Immersion Lithography at 157 nm", J. Vac. Sci. Technol. B., Vol. 19, No. 6, November/December 2001, pp. 2353-2356 BBR M. Switkes et al., "Immersion Lithography: Optics for the 50 nm Node", 157 Anvers-1, September 4, 2002 Date Considered: Examiner Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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